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Correction to

Highly-sensitive wafer-scale transfer-free graphene MEMS condenser microphones (Microsystems & Nanoengineering, (2024), 10, 1, (27), 10.1038/s41378-024-00656-x)

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CORRECTION

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Correction: Highly-sensitive wafer-scale transferfree graphene MEMS condenser microphones

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After publication of this article¹, it was brought to our attention that *two pressure values* were not correctly copied from the submitted original work to the published version. **Correction 1 (from PDF, Page 4 of 9)**: "These membranes show resonance frequencies above the audible range $(f_{01} > 20 \text{ kHz})$ at 1×10^3 mbar by piezo-shaker actuation". The described phrase needs to be changed reporting the right pressure value of 1×10^{-3} mbar. The new phrase will be: "*These membranes show resonance frequencies above the audible range (following)* at 1×10^{-3} mbar. The new phrase will be: "*These membranes show resonance frequencies above the audible range (following)* at 1×10^{-3} mbar by piezo-shaker actuation".

Correction 2 (from PDF, Page 4 of 9): "Energy losses and dampening are minimized due to the low pressure of 1×10^3 mbar". Again, the described phrase needs to be changed reporting the right pressure value of 1×10^{-3} mbar. The new phrase will be: "Energy losses and dampening are minimized due to the low pressure of 1×10^{-3} mbar".

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